

MAR 04 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: HO et al.

Attorney Docket No.: LAM1P152/P0692

Application No.: 09/782,446

Examiner: VINH, Lan

Filed: February 12, 2001

Group: 1765

Title: USE OF AMMONIA FOR ETCHING
ORGANIC LOW-K DIELECTRICS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to Commissioner for Patents, Washington, D.C. 20231 on February 26, 2003.

Signed

Sue Funchess

Sue Funchess

AMENDMENT A TRANSMITTALCommissioner for Patents
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims After Amendment		Highest Previously Paid For	Present Extra	Small Entity Rate Fee	Large Entity Rate Fee
Total Claims	17	MINUS	20	0	x 9 =	x 18 = \$-0-
Independent Claims	3	MINUS	3	0	x 42 =	x 84 = \$-0-
Multiple Dependent Claim Present and Fee Not Previously Paid					\$140.00	\$280.00
				Total	\$	\$-0-

Applicant(s) hereby petition for a one month extension(s) of time to respond to the aforementioned Office Action.

Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0388 (Order No. LAM1P152).

Enclosed is our Check No. 2260 in the amount of \$110.00 to cover the additional claim fee and/or extension of time fees.

Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 50-0388 (Order No. LAM1P152).

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP*Michael Lee*Michael Lee
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Berkeley, CA 94704-0778



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PATENT

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Signed Sue Funchess
Sue Funchess

AMENDMENT A

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated November 18, 2002, please amend the above-identified patent application as follows:

In the Specification:

On page 1, lines 7-20, please amend the paragraphs as follows:

"This application is also related to the commonly assigned U.S. Patent Application No.: [] (Attorney Docket No. LAM1P147/P0675)] 09/782,185 entitled UNIQUE PROCESS CHEMISTRY FOR ETCHING ORGANIC LOW-K MATERIALS, by Helen H. Zhu, filed concurrently herewith and incorporated herein by reference.

This application is related to the commonly assigned U.S. Patent Application No.: [] (Attorney Docket No.: LAM1P149/P0685)] 09/782,678 entitled POST-ETCH PHOTORESIST STRIP WITH O2 AND NH3 FOR ORGANOSILICATE